

high speed piezo translation stages

nanoSX 400 line

- 450µm travel range in X
- integrated capacitive direct metrology
- excellent trajectory trueness
- 12.5 mm central aperture
- high load capability
- advanced reliability and robustness

applications:

- nanopositioning
- micro scanning
- scanning microscopy
- surface analysis
- metrology and alignment

Concept

The nanoSX400 line one axis translation stage offers a large stroke, a central clearance and temperature compensation in a compact package. Trajectory trueness even at higher loads and appropriate stiffness are major advantages compared to competitive systems available on the market.

Vacuum and cryogenic versions are available on demand as well as body material variations of invar, superinvar, aluminum or titanium.

An optional external sensor preamplifier (version "extern" / "digital") offers independence from cable length.

Specials

The highest positioning linearity accuracy, stability, and reproducibility are achieved in closed loop operation when used in combination with the high resolution capacitive direct measuring feedback system from *piezosystem jena*.

The threading holes in the stage center offer a wide range of possible stage configurations.

By combination of two systems nanoSX 400 easily a nanoSXY 400 combination or a long travel range nanoSX 800 system can be created.



fig.: nanoSX 400

Mounting/Installation

Piezo actuators generate a pressure force to effect the resulting motion based on a solid state phenomena. The resolution is only limited by the noise of the amplifier and metrology. Such devices are neither affected by magnetic fields nor do they produce them. In cryogenic environments they function down to almost zero Kelvin. There is an associated decrease in the extension behavior. In vacuum conditions piezo actuators can be used at pressure below 10Pa. They should not be operated in the pressure range from 10Pa to 10kPa due to the greatly reduced dielectric breakdown strength of air.

The raster tapped and thru holes allow easy integration of the stage into any application or mechanical setup.





technical data:

series nanoSX		unit	nanoSX 400	nanoSX 400 CAP EXTERN	nanoSX 400 CAP DIGITAL
part. no.		-	T-124-00	T-124-06 / (E)	T-124-06D
axis		-	х	х	х
motion open loop (±10%)*		μm	450	450	450
motion closed loop (±0,2%)*		μm	-	350	350
capacitance (±20%)**		μF	2x3.5	2x3.5	2x3.5
integrated measurement system		-	-	capacitive	capacitive
resolution***		nm	0.6	1	1
typ. repeatability		nm	-	20	20
typ. nonlinearity		%	-	0.02	0.02
resonant frequency (X/Y/Z)		Hz	450/ 3000 / 3000	400 / 2500 / 2500	400 / 2500 / 2500
additional load = 50g		Hz	350	300	300
additional load = 100g		Hz	280	260	260
additional load = 300g		Hz	130	125	125
stiffness		N/µm	0.35 / 5.0 / 5.0	0.35 / 5.0 / 5.0	0.35 / 5.0 / 5.0
push/pull force capacity		Ν	100/100	100/100	100/100
max. load		N	100	100	100
ro	II	µrad	3	3	3
rotational error pit	tch	µrad	3	3	3
ya	W	µrad	3	3	3
voltage range		V	-20+130	-20+130 -20+130	
connector	voltage	-	ODU 3pin	ODU 3pin	D-Sub 15
CONNECTOR	sensor	-	-	ODU 4pin	D-Sub 15
material		-	stainless steel / aluminum		
dimensions (I x w x h)		mm	60 x 60 x 10	60 x 75 x 20	60 x 75 x 20
central aperture		mm	Ø12.5	Ø12.5	Ø12.5
weight		g	150	260	260

typical value measured with 30V300nanoX amplifier

** typical value for small electrical field strength
*** The resolution is only limited by the noise of the power amplifier and metrology.

recommended configurations:

actuator	nanoSX 400	T-124-00	
amplifier / controller	2 x 30V300 nanoX	E-468-011	
actuator amplifier / controller	nanoSX 400 CAP extern*T-128-04E2 x 30V300 nanoX CLEE-468-111*identical to nanoSX 400 CAP, except the external senor amplifierbetween stage and controller inside the cable extension.		
actuator	nanoSX 400 CAP	T-124-06	
amplifier / controller	ENT 40/20 (230V / 115V)	E-103-13/E-103-14	
casing	63 TE housing 19"	E-103-90	
actuator	nanoSX 400 CAP DIG	T-124-06D	
amplifier	30DV50	E-754-300	

Pay attention please to the "handling instructions" you can download from our homepage.